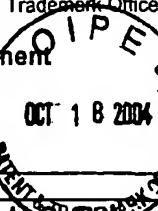


Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-583002	Application No. 10/718,832
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))			
		Applicant Y. Long He et al.	
		Filing Date November 21, 2003	Group Art Unit 1763



U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
W	AA	5,843,847	12/01/1998	Pu et al.			
W	AB	6,436,812	8/20/2002	Lee ,			
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	AH						
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Foreign Patent Documents or Published Foreign Patent Applications							
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No
W	AJ	61-171127	8/1/1986	Japan (English abstract only)			
	AK						
	AL						
	AM						
	AN						

Other Documents (include Author, Title, Date, and Place of Publication)		
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W	AO	M. Oda et al. "Xray mask fabrication technology for...". Journal of Vacuum Science & Technology B 14(6):4366-4370, Nov-Dec. 1996.
W	AP	P. E. Riley et al. "Implementation of Tungsten Metallization In Multilevel Interconnection Technologies". IEEE Transactions on Semiconductor Manufacturing 3(4): 150-157, November 1990.
	AQ	
	AR	

Examiner Signature 	Date Considered 11/21/05
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	